

Kaushik Varma Sagi

List of Publications by Year in descending order

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#	ARTICLE	IF	CITATIONS
1	Chemical Mechanical Polishing of Chemical Vapor Deposited Co Films with Minimal Corrosion in the Cu/Co/Mn/SiCOH Patterned Structures. ECS Journal of Solid State Science and Technology, 2017, 6, P276-P283.	0.9	40
2	Chemical Mechanical Polishing and Planarization of Mn-Based Barrier/Ru Liner Films in Cu Interconnects for Advanced Metallization Nodes. ECS Journal of Solid State Science and Technology, 2017, 6, P259-P264.	0.9	12
3	Citric Acid as a Complexing Agent in Chemical Mechanical Polishing Slurries for Cobalt Films for Interconnect Applications. ECS Journal of Solid State Science and Technology, 2017, 6, P594-P602.	0.9	59
4	Role of Ce ³⁺ Ions in Achieving High Silicon Nitride Polish Rates. ECS Journal of Solid State Science and Technology, 2017, 6, P898-P903.	0.9	14
5	Potassium Permanganate-Based Slurry to Reduce the Galvanic Corrosion of the Cu/Ru/TiN Barrier Liner Stack during CMP in the BEOL Interconnects. ECS Journal of Solid State Science and Technology, 2016, 5, P256-P263.	0.9	18
6	Mitigation of corrosion challenges for barrier films at advanced nodes. , 2016, , .		0
7	Investigation of Guanidine Carbonate-Based Slurries for Chemical Mechanical Polishing of Ru/TiN Barrier Films with Minimal Corrosion. ECS Journal of Solid State Science and Technology, 2014, 3, P227-P234.	0.9	14
8	Role of Guanidine Carbonate and Crystal Orientation on Chemical Mechanical Polishing of Ruthenium Films. ECS Journal of Solid State Science and Technology, 2013, 2, P445-P451.	0.9	41